

ABSTRACT OF THE DISCLOSURE

To provide a pattern formation method capable of forming a pattern by cleaning a liquid droplet ejection head without causing problems during the liquid droplet ejection operation, when the liquid droplet ejection head stored with a storage solution is used again, a pattern formation method includes: filling a passage including a liquid droplet ejection head and a conduit to feed a functional solution to the liquid droplet ejection head with purified water; filling the passage with a solvent dissolving both the purified water and a solvent contained in the functional solution, filling the passage with the solvent contained in the functional solution, surface treating a substrate by forming a lyophobic film on a region surrounding a pattern formation region defined on the substrate; and disposing liquid droplets on the pattern formation region with the liquid droplet ejection head.